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20. An apparatus according to claim 1, wherein said laser beam is a harmonic of a laser.

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21. An apparatus according to claim 2 further comprising a stage for holding a substrate having a semiconductor film thereon,
wherein said semiconductor film is crystallized by irradiating with the laser beam.

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22. An apparatus according to claim 3 wherein said optical system for overlapping divided laser beams is a convex lens.

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23. An apparatus according to claim 3, wherein said laser beam is a harmonic of a laser.

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24. An apparatus according to claim 4 further comprising a stage for holding a substrate having a semiconductor film thereon,
wherein said semiconductor film is crystallized by irradiating with the laser beam.

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25. An apparatus according to claim 4 wherein said optical system for overlapping divided laser beams is a convex lens.

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26. An apparatus according to claim 4, wherein said laser beam is a harmonic of a laser.

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27. An apparatus according to claim 5 further comprising a stage for holding a substrate having a semiconductor film thereon,
wherein said semiconductor film is crystallized by irradiating with the laser beam.

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29. An apparatus according to claim 8 wherein said slit comprises at least one of the group consisting of glass, quartz, ceramic, and metal.

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30. An apparatus according to claim 8 wherein said optical system for overlapping divided laser beams is a convex lens.

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31. An apparatus according to claim 8, wherein said laser beam is a harmonic of a laser.

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32. An apparatus according to claim 11 further comprising a stage for holding a substrate having a semiconductor film thereon,
wherein said semiconductor film is crystallized by irradiating with the laser beam.

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33. An apparatus according to claim 11 wherein said slit comprises at least one of the group consisting of glass, quartz, ceramic, and metal.

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34. An apparatus according to claim 11 wherein said optical system for overlapping divided laser beams is a convex lens.

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35. An apparatus according to claim 11, wherein said laser beam is a harmonic of a laser.

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36. An apparatus according to claim 11 further comprising a stage for holding a substrate having a semiconductor film thereon,
wherein said semiconductor film is crystallized by irradiating with the laser beam.

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~~36~~ 36 An apparatus according to claim ~~14~~ 13 wherein said optical system for overlapping divided laser beams is a convex lens.

~~37~~ 37 An apparatus according to claim ~~14~~ 13, wherein said laser beam is a harmonic of a laser.--
